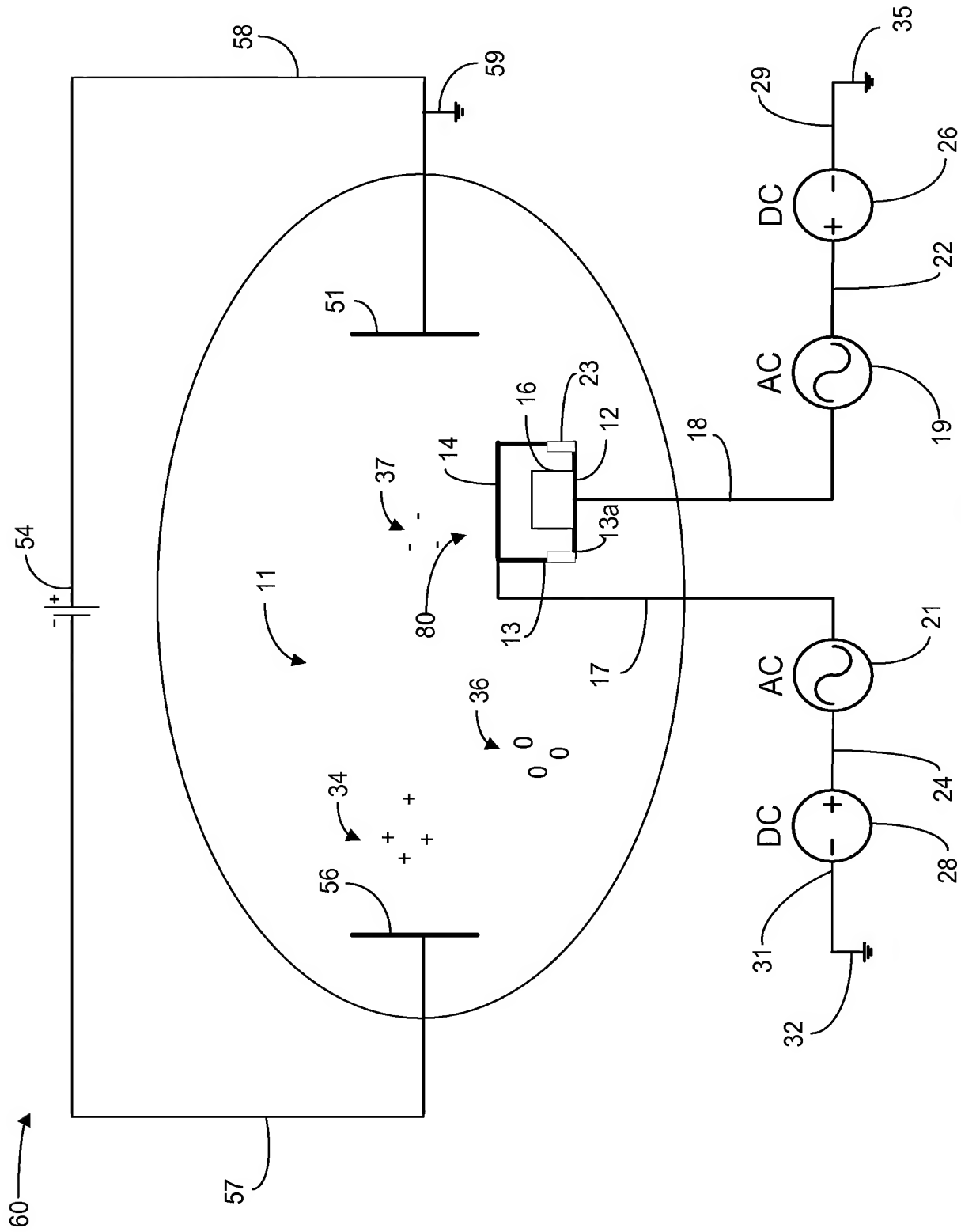


Fig. 1

Method and Apparatus for Low Energy Electron Enhanced Etching of
Substrates in an AC or DC Plasma Environment Inventors: Martin, et al.
Page 3 of 6

Method and Apparatus for Low Energy Electron Enhanced Etching of Substrates in an AC or DC Plasma Environment Inventors: Martin, et al.

Page 3 of 6



REPLACEMENT SHEET

Method and Apparatus for Low Energy Electron Enhanced Etching of
Substrates in an AC or DC Plasma Environment

Inventors: Martin, et al.

Page 4 of 6

Fig. 4

